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U.S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate
SPM	6,052,478	04/18/00	Wihl et al.	382	144	
SPM	4,579,455	04/01/86	Levy et al.	356	394	
SPM	4,851,978	07/25/89	Ichihara	362	268	
SPM	5,763,123	06/09/98	Shishido et al.	430	30	

FOREIGN PATENT DOCUMENTS

	Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No
SPM	7-86647	09/20/95	Japan	—	—	No
SPM	2526986	06/14/96	Japan	—	—	No
SPM	1290276	11/22/89	Japan	—	—	Abstract
SPM	5-45051	07/08/93	Japan	—	—	Abstract

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

SPM	S. Wolf and R.N. Tauber, "Silicon Processing for the VLSI Era" <i>Lithography II: Optical Aligners and Photomasks</i> , pg. 630-635

Examiner	Mohamedulla	Date Considered	5/25/03
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